

IN THE CLAIMS:

Please amend claims 1, 5, 6 and 8 as follows. Cancel claims 3 and 9 - 12.

1. (Amended) A filter arrangement which comprises a substrate (1) on which are provided a thin-film bandpass filter and a thin-film notch filter, which filters are coupled to one another.
5. (Amended) A filter arrangement as claimed in claim 4, characterized in that the filter arrangement of resonators comprises bulk acoustic wave resonators, surface acoustic wave resonators, or ceramic electromagnetic resonators.
6. (Amended) A filter arrangement as claimed in claim 5, characterized in that the bulk acoustic wave resonator comprises a resonator unit and a reflection element (2) which is arranged between the substrate (1) and the resonator unit.
8. (Amended) A method of manufacturing a filter arrangement, which comprises a substrate (1) and provided thereon a bandpass filter of bulk acoustic wave resonators and a notch filter, by which method
- a second electrode (5), a piezoelectric layer (4), and a first electrode (3) are provided on a passivating layer formed on a carrier layer and are structured such that at least one resonator unit, a capacitor and an inductor are created,
 - a reflection element (2) is deposited on those portions of the first electrode (3) which belong to the resonator unit,
 - a substrate (1) is fastened on the entire assembly, and the carrier layer is removed.